

### NON-EQUILIBRIUM SYNTHESIS OF SEMICONDUCTOR ALLOYS FOR **ENERGY APPLICATIONS**



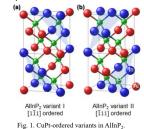
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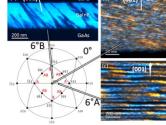
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Overview: We are exploring the synthesis under equilibrium/non-equilibrium conditions of semiconductor alloys critical to SSL to impose top-down influence on the formation of atomic-scale microstructures.

# I. Introduction

On-going work at NREL addresses order/disorder Al, In1, P confinement structures, which are predicted to surpass the power-conversion efficiency of current materials used for red/amber LEDs as components of color-mixed LEDs.





Strongly CuPt-ordered GaInP/GaAs [1] and Fig. 2. (001) pole figure and ordered domain structure in Ga0 521 no 48P (a) GaInAs/InP [2] have been studied extensively. double-variant ordered/disordered SL; (a) single-variant ordered layer embedded in GaAs [ variant-I, variant-II, disordered (or GaAs)].

B. Lattice-mismatched heteroepitaxy

direct-gap AIInP compositions.

group-III composition

For LEDs, metamorphic GaInAs grades can

be used to accommodate the mismatch of

Fig. 4. Metamorphic GaInAs grades with displacement

layers: (a) 220 dark-field image; (b) EDX map showing

Two ordered variants form during grown on exact (001) and [111]A offcut substrates. One ordered variant dominates for [111]B offcut substrates.

Lattice-mismatch for Al, In1, P/GaAs:  $f_{AIInP} = (3.67\%) \cdot (1 - w) + (-3.71\%) \cdot w$ 

Less information is available on ordered

Al\_In<sub>1</sub>  $_{w}$ P/GaAs is lattice matched for w~0.5, but the bandgap is indirect for w>0.4 [3].

# **II. Experiment**

AllnP/GaAs.

This study aims to control ordering using non-equilibrium synthesis and characterize the resulting ordered/disordered microstructures.

A. Plasma-enhanced MOCVD (PE-MOCVD)

PE-MOCVD allows decomposition of precursors at low temps. [4] Plasma can be created by RF excitation at low pressures.

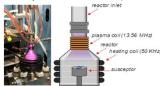
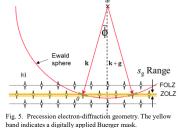


Fig. 3. PE-MOCVD growth at SDSMT: (a) photo; (b) diagram showing reactor inlet, coil for exciting plasma, quartz reactor, coil for heating susceptor, and graphite susceptor.

#### C. TEM precession diffraction

Precession electron diffraction allows direct retrieval of structure factors for electron crystallography. A Buerger mask can be applied digitally to retain sharpness of the diffraction spots.



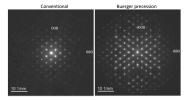


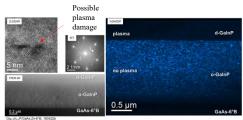
Fig. 6. Selected-area electron-diffraction patterns from Si: (left) conventional method (b) Buerger precession method (\$=30 mrad, sgRange=0.02 1/nm.)

# **III. Preliminary Results**

Initial growth experiments have studied PE-MOCVD to switch ordering on/off. TEM diffraction methods have been developed for order-parameter determination.

#### A. MOCVD/PE-MOCVD ordered/disordered GaInP<sub>2</sub>

In early growth runs, we demonstrated the suppression of ordering in GaInP/GaAs by application of plasma.



B. Epitaxial growth of AlInP<sub>2</sub> Further optimization of AlInP growth conditions is needed.

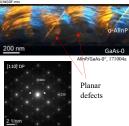


Fig. 7. TEM data from GaInP/GaAs film showing the use of PE-MOCVD to eliminate ordering

#### C. Analysis of TEM precession diffraction patterns

Correct structure factors for these alloys are needed to accurately determine order parameter by diffraction methods. Anion displacements resulting from cation ordering have been shown to have a significant effect. The displacement distances can be computed from the valence-force-field model.

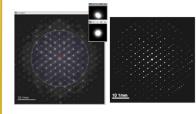


Fig. 9. PE-MOCVD from TMAl on TEM grid; (a) STEM bright-field; (b) SEM; (c) TEM lattice image; (d) electron-diffraction pattern consistent with fcc Al.

Automated measurement of electrondiffraction-spot intensities is used for refinement of simulated patterns.

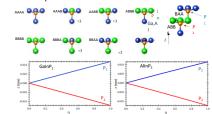


Fig. 10. VFF analysis gives a nearly linear variation of anion displacement with order parameter

The mean anion displacement can be related to the order parameter  $\eta$  by weighing the displacement for all possible tetrahedral configurations by the probability of each configuration given a global value of n.

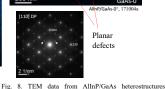
# **IV. Conclusions**

We aim to create greater control of ordering, phase separation, and strain relaxation in III-Vs, through the use of non-equilibrium synthesis, for photovoltaic and solid-state lighting applications. Ordered/disordered structures synthesized by MOCVD/PE-MOCVD are currently under investigation by TEM precession diffraction. We intend to expand characterization of these materials using optical spectroscopy and high-resolution X-ray nano-diffraction methods using DOE facilities.

### References: [1] L. C. Su, et al. J. Appl. Phys. <u>75</u>, 5135. T. Y. Scong, et al., J. Appl. Phys. <u>75</u>, 7852. T. M. Christian, et al., J. Appl. Phys. <u>114</u>, 74505. A. D. Huelsman, et al., Appl. Phys. <u>114</u>, 74505. C. S. Own, et al., Rev. Sci. Instrum. <u>76</u>, 33703. [5] J. H. Li, et al., J. Appl. Phys. 91, 9039.

#### Acknowledgement:

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Improvements are needed to grow high-quality AlInP layers. Nonetheless, strong double-variant ordering is obtained.

Plasma activation used to eliminate ordering